

Amendments to the Specification

Please amend the **TITLE** as follows:

40 MICROELECTROMECHANICAL STRAIN GAUGE WITH
FREQUENCY DETECTOR

Please amend the **ABSTRACT** as follows:

45 A microelectromechanical system (MEMS) strain gauge includes at
least one flexible arm that can be caused to oscillate. Transverse strain on
the arm changes the resonant frequency of the arm. A detector
communicating with the flexible arm may detect the frequency of oscillation
to provide , ~~providing~~ an indication of the transverse strain of the substrate.